# 40,00 10692

## , 00 07% c

### Electronic Version v1.1 Stylesheet Version v1.1

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	To correct the Correspondent's Name and Address due to an error in the Customer Number with the initial submission. Also, please correct the spelling of the inventor lan Robson McFadyen.

### **CONVEYING PARTY DATA**

Name	Execution Date
Alexander Bietsch	07/21/2004
Michael W. Chaw	06/15/2004
Ashok Lahiri	07/30/2004
lan Robson McFadyen	06/16/2004
Bruno Michel	07/21/2004
Mark C. Thurber	07/21/2004

### **RECEIVING PARTY DATA**

Name:	Hitachi Global Storage Technologies Netherlands B.V.	
Street Address:	ocatellikade 1	
Internal Address:	Parnassustoren	
City:	1070 AZ Amsterdam	
State/Country:	NETHERLANDS	

### PROPERTY NUMBERS Total: 1

Property Type	Number
Application Number:	10692992

### **CORRESPONDENCE DATA**

Fax Number: (512)479-3923

Correspondence will be sent via US Mail when the fax attempt is unsuccessful.

Email: Michael.Noe@bracewellgiuliani.com

Correspondent Name: Bracewell & Giuliani LLP

Address Line 1: P.O. Box 61389

Address Line 2: Attn: Michael E. Noe, Jr.
Address Line 4: Houston, TEXAS 77208-1389

NAME OF SUBMITTER: Michael E. Noe, Jr.

PATENT

REEL: 016324 FRAME: 0109

500042260

#### Total Attachments: 22

source=HSJ920030074US1.ASSIGNMENT MATERIALS#page1.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page2.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page3.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page4.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page5.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page6.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page7.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page8.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page9.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page10.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page11.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page12.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page13.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page14.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page15.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page16.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page17.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page18.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page19.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page20.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page21.tif source=HSJ920030074US1.ASSIGNMENT MATERIALS#page22.tif

Substitute Form PTO -1595	RECORDATION FO	Patent Docket No.		
	PATENT	HSJ920030074US1		
To The Honorable Commissioner	of Patents and trademarks: Ple	ease record the attached origin	nal documents or copy thereof.	
1. Name of conveying party(ies	s):	Execution date:		
Alexander Bietsch		July 21, 2004		
Michael W. Chaw		June 15, 2004		
Ashok Lahiri		<u>July 30, 2004</u>		
Ian Robson McFadyen		June 16, 2004		
Bruno Michel Mark C. Thurber		July 21, 2004		
		July 21, 2004		
2. Name and address of receiving		3. Nature of conveyance:		
Hitachi Global Storage Techno	logies Netherlands B.V.			
Locatellikade 1		∆ Assignment	☐ Merger	
1076 AZ Amsterdam P.O. Box 75215		☐ Security Agreement	Change of Name	
1070 AE Amsterdam			he correspondent's address	
The Netherlands		due to wrong Customer	Number with initial	
		submission)		
4. Application number(s) or part	tent number(s):	Execution/Fi	lling/Issue Date	
Navy Patent Application or	ropution data of application	•		
☐ New Patent Application, ex	ecution date of application		tion Date	
	: <u>10/692,992</u>	October 24, 2003		
Filing Date				
Patent Number:				
	*******	lssu	e Date	
5. Name and address of party to whom correspondence		6. Total number of applic	cations and patents involved:	
concerning document should be mailed:		1		
7. Total fee (37 CFR 3.41) \$40.0			1) \$ <u>40.00</u>	
Customer Number 48583		☐ Enclosed Check		
		Authorized to be ch	arged to deposit account	
Bracewell & Giulia	ni LLP	Authorized to charg	e any deficiency to deposit	
P.O. Box 61389		account		
Houston, Texas 772	08-1389	8. Deposit account numb	er:	
		(Attach duplicate copy of thi	s page if paying by deposit account)	
DO NOT USE THIS SPACE				
9. Statement and signature				
To the best of my knowledge and belief, the foregoing information is true and correct and any attached copy is				
a true copy of the original document.				
Betty J. Kirk	_ selos	1 IXX	July 28, 2005	
Name of Person Signing	Sig	bature	Date	
T-4-1	han of managinality division		manta. O	
I otal num	der of pages including cover	sheet, attachments, and docum	nents: 9	

ASSIGNMENT			
Whereas, I,			
(1) Alexander Bietsch of Rueschlikon, Switzerland;			
(2) Michael W. Chaw of San Jose, Santa Clara County, California;			
(3) Ashok Lahiri of Mainz, Germany;			
(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;			
(5) Bruno Michel of Adliswil, Switzerland; and			
(6) Mark C. Thurber of San Jose, Santa Clara County, California			
have invented certain improvements in			
SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING			
and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) (1)			
Whereas, Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands, (hereinafter called HITACHI), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;  Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to HITACHI, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to HITACHI, its successors and assigns; and we hereby agree that HITACHI may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by HITACHI.			
(1) Signed at on, 2004.			

PATENT REEL: 016324 FRAME: 0112

Alexander Bietsch

(2) Signed at	IAN TOUE	on	6/15	, 2004.
		$\sim$	PL	Michael W. Chaw
(3) Signed at		on		, 2004.
			_ ::::	Ashok Lahiri
(4) Signed at	an Jose			, 2004.  Ian R. McFadyen
			<u> , , , , , , , , , , , , , , , , ,</u>	Ian R. McFadyen
(5) Signed at		on		, 2004.
				Bruno Michel
(6) Signed at		on		, 2004.
				Mark C. Thurber

Whereas, I,

- (1) Alexander Bietsch of Rueschlikon, Switzerland;
- (2) Michael W. Chaw of San Jose, Santa Clara County, California;
- (3) Ashok Lahiri of Mainz, Germany;
- (4) Ian Robson McFadyen of San Jose, Santa Clara County, California;
- (5) Bruno Michel of Adliswil, Switzerland; and
- (6) Marc C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

### SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

Their I Glate waters and in the About the or (Data Inventor Girmod

and executed, resp	ectively, a Unite	a States patent applica	mon meretor on (Date	: mvemor signed
Declaration) (1)	7/21	, 2004; <b>(2)</b> _		, 2004;
(3)	,	, 2004; (4)	,	, 2004;
(5)		, 2004; and (5)	7121	, 2004.
• • • • • • • • • • • • • • • • • • • •				

Whereas, Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands, (hereinafter called HITACHI), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to HITACHI, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to HITACHI, its successors and assigns; and we hereby agree that HITACHI may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by HITACHI.

Ruschlikon on July 21	, 2004.
<i>3</i> /	•
Alexander But	
the xander but	Alexander B

1

(2) Signed at		on			, 2004.
	-	·	]	Michael W	. Chaw
(3) Signed at		on			, 2004.
					Lahiri
(4) Signed at _		on			, 2004.
				Ian R. Mc	Fadyen
(5) Signed at _	Ruschlikon	on	7/21		, 2004.
		B	run Mi	chel	
					Michel
(6) Signed at _		on			, 2004.
				Marc C. T	hurber

ASSIGNMENT	
Whereas, I,	
(1) Alexander Bietsch of Rueschlikon, Switzerland;	
(2) Michael W. Chaw of San Jose, Santa Clara County, California;	
(3) Ashok Lahiri of Mainz, Germany;	
(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;	
(5) Bruno Michel of Adliswil, Switzerland; and	
(6) Marc C. Thurber of San Jose, Santa Clara County, California	
have invented certain improvements in	
SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING	
and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) (1), 2004; (2), 2004;	
(3) 7 3 0 .2004; (4)	
(3) 7 3 , 2004; (4) , 2004; (5) , 2004; and (5) , 2004.	
Whereas, Hitachi Global Storage Technologies Netherlands B.V., having a place of business at Locatellikade 1, Parnassustoren, 1076 AZ Amsterdam, The Netherlands (hereinafter called HITACHI), desires to acquire the entire right, title and interest in the sai application and invention, and to any United States and foreign patents to be obtained therefor;  Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged we, the above named, hereby sell, assign, and transfer to HITACHI, its successors and assigns the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letter Patent granted upon the invention set forth in said application to HITACHI, its successors and	i, s, e d
assigns; and we hereby agree that <b>HITACHI</b> may apply for foreign Letters Patent on sai invention and we will execute all papers necessary in connection with the United States an foreign applications when called upon to do so by <b>HITACHI</b> .	d
(1) Signed at on, 2004	٠.

Alexander Bietsch

(2) Signed at _		on	, 2004.
			Michael W. Chaw
(3) Signed at _	Capertina	on	7/30 ,2004.
	A. C. 149		7/30,2004.
			Ashok Lahiri
(4) Signed at _		on	, 2004.
			Ian R. McFadyen
(5) Signed at _		on	, 2004.
		-	Brino Michel
(6) Signed at _	· · · · · · · · · · · · · · · · · · ·	on	, 2004.
			Marc C. Thurber

2

** 1	•		•
\ <b>\</b> /	h	ereas,	ı
vv	11	Ci Cas.	ъ.

- (1) Alexander Bietsch of Rueschlikon, Switzerland;
- (2) Michael W. Chaw of San Jose, Santa Clara County, California;
- (3) Ashok Lahiri of Mainz, Germany;
- (4) Ian Robson McFadyen of San Jose, Santa Clara County, California;
- (5) Bruno Michel of Adliswil, Switzerland; and
- (6) Mark C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

### SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a				
Declaration) (1)	2004, (2) <u>2004, (2) </u>			2004
(3)(5)	, 2004; (4), 2004; and (6)	21	July	, 2004.
Whereas, Hitachi Globusiness at Locatellikade (hereinafter called HITACH application and invention, and	I), desires to acquire the e	AZ ntire r	Amsterda ight, title	m, The Netherlands, and interest in the said
Now therefore, for a we, the above named, hereby the entire right, title and inte United States and foreign co United States application, ar Patent granted upon the inversassigns; and we hereby agre invention and we will execut foreign applications when cal	rest in the said application untries, and all rights of paid we request the Commination set forth in said applies that HITACHI may agate all papers necessary in	and in priority ssioner cation oply for conne	ACHI, its nvention the resulting r of Paten to HITA or foreign	successors and assigns, herein disclosed for the from the filing of said ts to issue any Letters CHI, its successors and Letters Patent on said
(1) Signed at	on _			, 2004.
	**************************************			Alexander Bietsch

(2) Signed at	on	, 2004.
-		Michael W. Chaw
(3) Signed at	on	, 2004.
-		Ashok Lahiri
(4) Signed at	on	
-		Ian R. McFadyen
(5) Signed at	on	, 2004.
-		Bruno Michel
(6) Signed at El Salto, Jalisco, MEXIC	co on 21	July , 2004.
_	Mach	C. Thuber
	-	Mark C. Thurber

Received in the U.S.P.T.O.

In re Application of: ALEXANDER BIETSCH ET AL.

Application No. 10/787,476 Filing Date: FEBRUARY 26, 2004

Attorney Docket No.: HSJ920030074US1

Title: SYSTEM, METHOD AND APPARATUS FOR MULTILEVEL UV MOLDING

LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

### **ENCLOSED HEREWITH:**

1. This Return Receipt Postcard;

- 2. Notice of Recordation of Assignment with Patent Application No. and Filing Date (in duplicate); and
- 3. **Executed Assignment**

HITACHI Global Storage Technologies Attorney Docket No.: HSJ920030074US1

Our File No. 041131.000032 - Mailed: August 17, 2004 - MEN:bk

XC: HITACHÍ



Bracewell & Patterson, L.L.P. P.O. Box 61389 Houston, TX 77208-1389

Received in the U.S.P.T.O.

In re Application of: ALEXANDER BIETSCH ET AL.

Application No. 10/787,476 Filing Date: FEBRUARY 26, 2004

Attorney Docket No.: HSJ920030074US1

Title: SYSTEM, METHOD AND APPARATUS FOR MULTILEVEL UV MOLDING

LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

**ENCLOSED HEREWITH:** 

This Return Receipt Postcard;

This Return Receipt Postcard;
Notice of Recordation of Assignment with Potent Application No. and 2. 30 : 11 11 5 311 100 L Filing Date (in duplicate); and

Executed Assignment

HITACHI Global Storage Technologies

Attorney Docket No.: HSJ920030074US1

Our File No. 041131.000032 - Mailed: August 17, 2004 MEN:bk

**PATENT** 

REEL: 016324 FRAME: 0120

ASSIGNMENT
Whereas, I,
(1) Alexander Bietsch of Rueschlikon, Switzerland;
(2) Michael W. Chaw of San Jose, Santa Clara County, California;
(3) Ashok Lahiri of Mainz, Germany;
(4) Ian Robson McFadyen of San Jose, Santa Clara County, California;
(5) Bruno Michel of Adliswil, Switzerland; and
(6) Mark C. Thurber of San Jose, Santa Clara County, California
have invented certain improvements in
SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING
and executed, respectively, a United States patent application therefor on (Date Inventor Signed Declaration) (1)
(hereinafter called HITACHI), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;
Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to HITACHI, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to HITACHI, its successors and assigns; and we hereby agree that HITACHI may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by HITACHI.
(1) Signed at on, 2004.

PATENT REEL: 016324 FRAME: 0121

Alexander Bietsch

On	, 2004.
mp	Michael W. Chaw
on	, 2004.
on Time	Ashok Lahiri
	<b>Tan R. McFadyen</b>
	Bruno Michel
on	, 2004.
	onononon

W	hereas,	I.

- (1) Alexander Bietsch of Rueschlikon, Switzerland;
- (2) Michael W. Chaw of San Jose, Santa Clara County, California;
- (3) Ashok Lahiri of Mainz, Germany;
- (4) Ian Robson McFadyen of San Jose, Santa Clara County, California;
- (5) Bruno Michel of Adliswil, Switzerland; and
- (6) Marc C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

### SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a United States patent application therefor on (Date Inventor Signed

Declaration) (1)	7/61	, 2004; <b>(2)</b>		, 2004;
(3)	, 	, 2004; (4)		, 2004;
(5)		, 2004; and (5)	7/2/	, 2004.
Whereas, 1	Hitachi Global S	torage Technologie	s Netherlands B.V.,	having a place of
			AZ Amsterdam,	<u> </u>

(hereinafter called HITACHI), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we, the above named, hereby sell, assign, and transfer to HITACHI, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to HITACHI, its successors and assigns; and we hereby agree that HITACHI may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by HITACHI.

(1) Signed at NUSCHINON on July 2/ , 2004  Mexander Buter		Alexa	nder Bietsch
(1) Signed at $\frac{NUSCH(NON)}{}$ on $\frac{JUVZ}{}$ , 2004		Alexander Butter	
M · · · · / / / / / / / / / / / / / / /	(1) Signed at Kuschlikon	on <u>July 21</u>	, 2004.

1

(2) Signed at	on			_, 2004.
			Michael V	V. Chaw
(3) Signed at	on			_, 2004.
(4) Signed at				k Lahiri
(4) Signed at	on			, 2004.
2 2 2 2			Ian R. Mo	cFadyen
(5) Signed at Rusukon	on	7/21		_, 2004.
		run M		
				Michel
(6) Signed at	on			_, 2004.
			Marc C. 7	 Thurber

**	ra	~
\ <b>\</b> \	hereas,	
* *	more cas.	

- (1) Alexander Bietsch of Rueschlikon, Switzerland;
- (2) Michael W. Chaw of San Jose, Santa Clara County, California;
- (3) Ashok Lahiri of Mainz, Germany;
- (4) Ian Robson McFadyen of San Jose, Santa Clara County, California;
- (5) Bruno Michel of Adliswil, Switzerland; and
- (6) Marc C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

### SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

and executed, respectively, a U Declaration) (1)	Inited States patent application therefor, 2004; (2), 2004; (4), 2004; and (5)	on (Date Inventor Signed, 2004;
(3) 7130	, 2004; (4)	, 2004;
(5)	, 2004; and (5)	, 2004.
business at Locatellikade 1 (hereinafter called HITACHI	bal Storage Technologies Netherland, Parnassustoren, 1076 AZ Amstell, desires to acquire the entire right, to any United States and foreign patent	erdam, The Netherlands, itle and interest in the said
we, the above named, hereby so the entire right, title and intered United States and foreign cour United States application, and Patent granted upon the invent assigns; and we hereby agreed invention and we will execute	valuable consideration, receipt whereo sell, assign, and transfer to HITACHI, est in the said application and inventionanties, and all rights of priority result if we request the Commissioner of Pation set forth in said application to HI that HITACHI may apply for force all papers necessary in connection we all papers necessary in connection which we also necessary in connection which we also necessary in connection which we also necessary in the connection whic	its successors and assigns, on therein disclosed for the ing from the filing of said atents to issue any Letters TACHI, its successors and ign Letters Patent on said
(1) Signed at	on	, 2004.
		Alexander Bietsch

(2) Signed at _		on _	, 2004.
			Michael W. Chaw
(3) Signed at _	Cupertina	on	7/30 ,2004.
	Capertino		Ashskulin
			Ashok Lahiri
(4) Signed at _		on	, 2004.
			Ian R. McFadyen
(5) Signed at _		on	
			Brino Michel
(6) Signed at _		on	, 2004.
			Marc C. Thurber

W	hereas.	1
- Y Y	nercas.	

- (1) Alexander Bietsch of Rueschlikon, Switzerland;
- (2) Michael W. Chaw of San Jose, Santa Clara County, California;
- (3) Ashok Lahiri of Mainz, Germany;
- (4) Ian Robson McFadyen of San Jose, Santa Clara County, California;
- (5) Bruno Michel of Adliswil, Switzerland; and
- (6) Mark C. Thurber of San Jose, Santa Clara County, California

have invented certain improvements in

## SYSTEM, METHOD, AND APPARATUS FOR MULTILEVEL UV MOLDING LITHOGRAPHY FOR AIR BEARING SURFACE PATTERNING

	, 2004; <b>(2)</b>	erefor on (Date Inventor Signed, 2004;
(3)	, 2004; <b>(4)</b>	, 2004;
(5)	, 2004; (2), 2004; (4), 2004; and (6) 21	July , 2004.
business at Locatellikad (hereinafter called HITAC	Global Storage Technologies Nether e 1, Parnassustoren, 1076 AZ A (HI), desires to acquire the entire right of the any United States and foreign p	Amsterdam, The Netherlands, ght, title and interest in the said
we, the above named, herely the entire right, title and in United States and foreign United States application, Patent granted upon the invassigns; and we hereby againvention and we will exer	a valuable consideration, receipt when by sell, assign, and transfer to HITA deterest in the said application and invocuntries, and all rights of priority rand we request the Commissioner vention set forth in said application to gree that HITACHI may apply for cute all papers necessary in connect alled upon to do so by HITACHI.	CHI, its successors and assigns, vention therein disclosed for the resulting from the filing of said of Patents to issue any Letters o HITACHI, its successors and foreign Letters Patent on said
		, 2004.

(2) Signed at	on	, 2004.
_		Mishael W. Chan
		Michael W. Chaw
(3) Signed at	on	, 2004.
_		Ashok Lahiri
(4) Signed at	on	, 2004.
		Ian R. McFadyen
(5) Signed at	on	, 2004.
	- <del>1 - 1 - 1</del> - 1 - 1 - 1 - 1 - 1 - 1 - 1 -	Bruno Michel
(6) Signed at El Salto, Jalisco, MEXICO	on 21	July , 2004.
	Mach	C. Thuber
		Mark C. Thurber

2

**RECORDED: 07/28/2005**